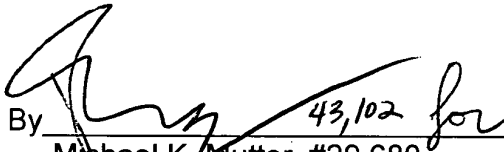


- ☐ Petition for ____ () month(s) extension of time pursuant to 37 C.F.R. §§ 1.17 and 1.136(a) is being filed, along with the necessary extension fees, together with the Notice of Appeal, concurrently herewith.
- ☒ No fee is required.
- ☐ A check in the amount of \$0.00 is enclosed.
- ☐ Please charge Deposit Account No. 02-2448 in the amount of \$0.00. This form is submitted in triplicate.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fees required under 37 C.F.R. §§1.16 or 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

By  43,102 for
Michael K. Mutter, #29,680

MKM/RLS/dsp
2342-107P

P.O. Box 747
Falls Church, VA 22040-0747
(703) 205-8000



PATENT
2342-0107P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Mitsuhiro HIRANO Conf.: 3165
Appl. No.: 08/813,200 Group: 2814
Filed: March 7, 1997 Examiner: S. RAO

#21/F
6/5/01
Purder

For: SUBSTRATE PROCESSING APPARATUS WITH LOCAL
EXHAUST FOR REMOVING CONTAMINANTS (AS AMENDED)

AMENDMENT

Assistant Commissioner of Patents
and Trademarks
Washington, D.C. 20231

May 22, 2001

Sir:

In reply to the Examiner's Office Action dated February 22, 2001, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please amend the claims as follows:

RECEIVED
MAY 31 2001
TO 2803 MAIL ROOM

- sub
G1
F1
10. (Four Times Amended) A substrate processing apparatus comprising:
- a substrate processing chamber for processing a substrate;
 - a load lock chamber;
 - a gas supply for supplying gas into said load lock chamber;
 - a chamber exhaust for exhausting said load lock chamber, said chamber exhaust including an atmospheric pressure vent line and a vacuum exhaust line, said